

[54] **WAFER PROBE PLATE HOLDER**

[75] Inventor: **Wataru Karasawa**, Yokohama, Japan

[73] Assignee: **Tokyo Electron Limited**, Tokyo, Japan

[\*\*] Term: **14 Years**

[21] Appl. No.: **360,754**

[22] Filed: **Jun. 2, 1989**

[52] U.S. Cl. .... **D10/103**

[58] Field of Search ..... **D10/46, 80, 103; D8/349, 399; 324/158 F, 158 P**

[56] **References Cited**

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*Primary Examiner*—Nelson C. Holtje  
*Assistant Examiner*—Antoine D. Davis  
*Attorney, Agent, or Firm*—Oblon, Spivak, McClelland, Maier & Neustadt

[57] **CLAIM**

The ornamental design for a wafer probe plate holder, as shown and described.

**DESCRIPTION**

FIG. 1 is a front elevational view of a wafer probe plate holder showing my new design, the rear, right and left side elevational views being identical; FIG. 2 is a top plan view; FIG. 3 is a bottom plan view; and FIG. 4 is a cross sectional view thereof taken along line 4-4' of FIG. 2 thereof.

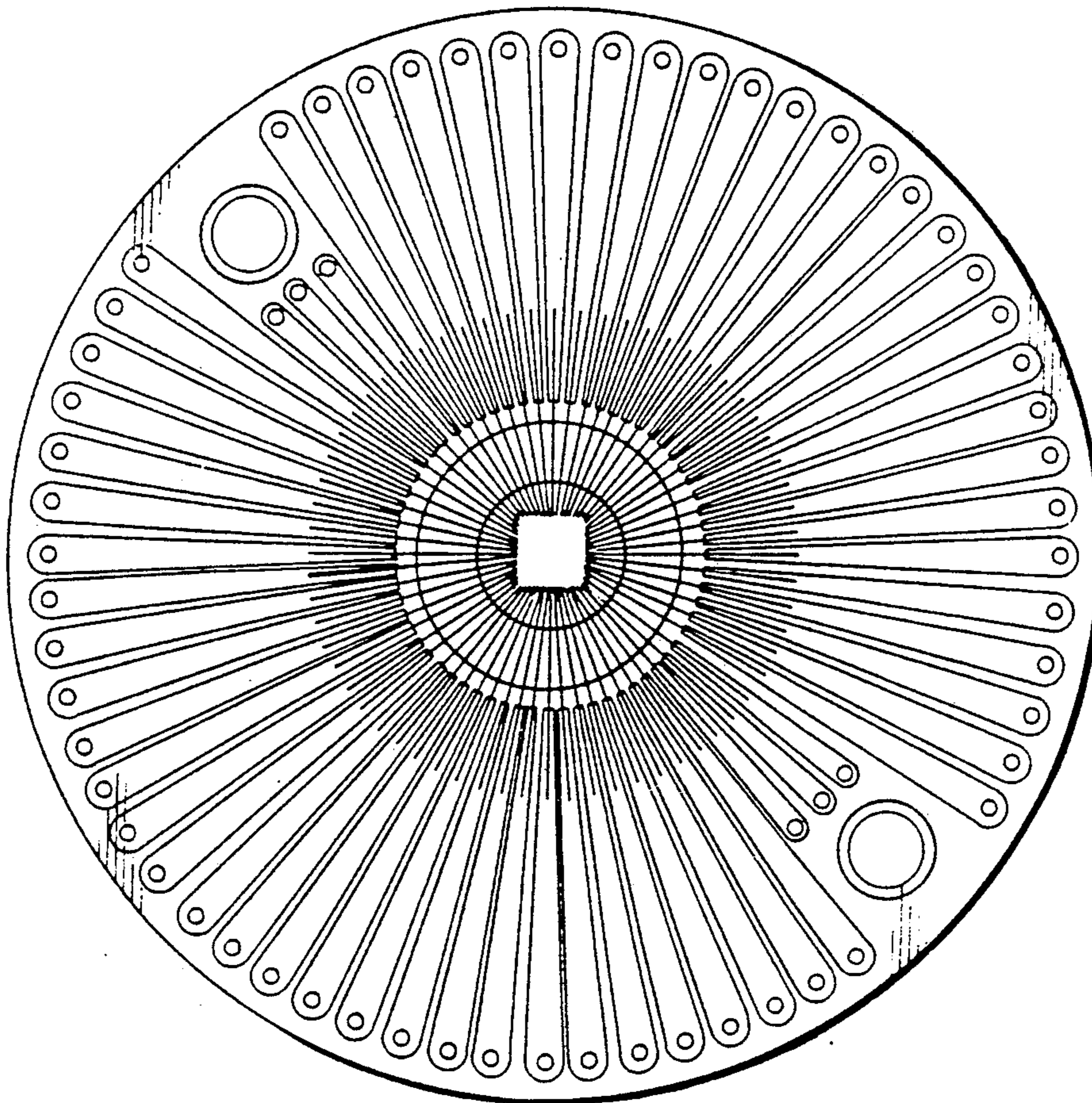


FIG. 1



FIG. 4



FIG. 2

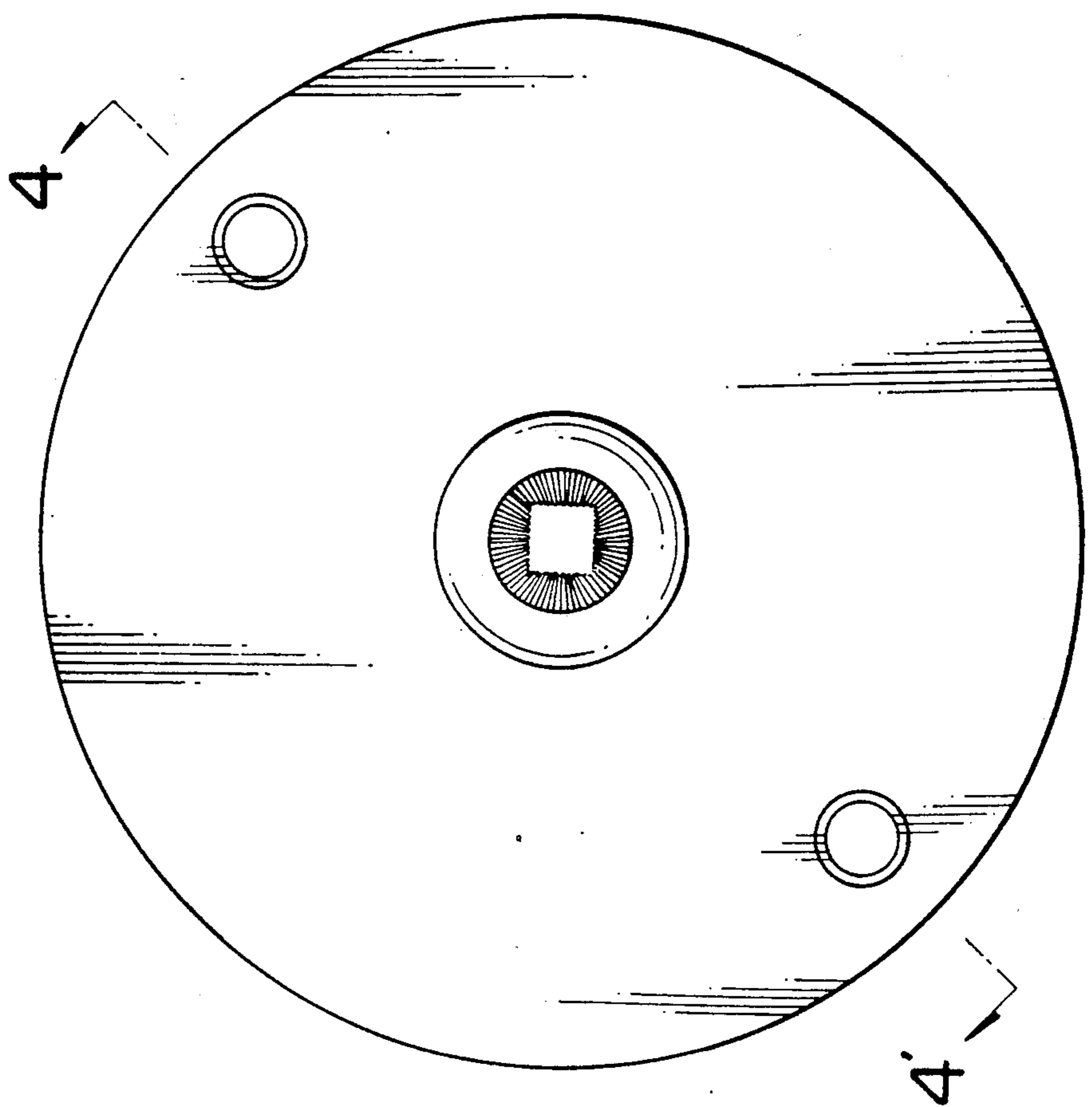


FIG. 3

